

**Amendments to the Drawings:**

A sheet attached in connection with the above-identified application containing new Figure 41 is being presented as a new formal drawing sheet.

Figure 41 is a modification of Figure 40 where the film-forming-supply means 135 is arranged outside the container.

## REMARKS

Applicants respectfully request reconsideration of the present application in view of the foregoing amendments and in view of the reasons that follow.

In the specification, paragraphs have been amended on pages 18 and 45.

No claims are currently being amended. Claims 1-22 and 25-54 remain pending in this application, where claims 21 and 25-53 are withdrawn from consideration.

### **Claim Rejections under 35 U.S.C. § 112, First Paragraph**

Claims 1-20, 22 and 54 are rejected under 35 U.S.C. 112, first paragraph, as allegedly failing to comply with the written description requirement. In particular, the Patent Office alleges that the features “. . . an evaporation mechanism, located outside said container,” and “directing means” constitute new matter. Applicants respectfully disagree.

The “directing means” coupled to said evaporation mechanism and said container and for using a transport gas to direct the evaporated film-forming material or the evaporated film-forming material precursor towards said substrate” of claim 1 is supported by the application as originally filed. For example, FIG. 26 illustrates gas ejection portions 37, which when the valve 19 is opened, eject an inert gas toward the substrate 32 through the gas ejection plate 34 as is explained in paragraphs 0075 and 0089 of the application as originally filed. Thus, FIG. 26 as described in the specification illustrates a directing means using a transport gas (the inert gas) to direct evaporated film-forming material or the evaporated film-forming material precursor towards the substrate.

The “evaporation mechanism, located outside said container” of claim 1 is supported by the application as originally filed. For example, at least paragraphs 0023 and 0024 of the application as filed disclose that the film-forming material supply means may be located outside the container. In this case, the evaporation mechanism, which is part of the film-forming material supply means, must necessarily be outside the container.

### Drawings

The drawings were objected to under 37 CFR 1.83(a) for allegedly not showing every feature of the invention as specified by the claims, namely for not showing the features “an evaporation mechanism, located outside said container,” and “directing means.”

With respect to the feature “an evaporation mechanism, located outside said container,” FIG. 40 of embodiment 4, for example, illustrates a film-forming-supply means 135 which includes an evaporation mechanism (evaporation dish). As discussed above, at least paragraphs 0023 and 0024 of the application as filed disclose that the film-forming material supply means may be located outside the container, and thus one skilled in the art would recognize that the film-forming-supply means 135, along with its evaporation mechanism, could be located outside the container in FIG. 40.

Nevertheless, new FIG. 41 has been added, where new FIG. 41 illustrates a modification of the embodiment of FIG. 40 where the film-forming-supply means 135 is arranged outside the container.

Further, as discussed above, at least FIG. 26 of the application, which illustrates the gas ejection portions 37 and the gas ejection plate 34, illustrates a “directing means.”

### Specification

The specification was objected to for allegedly failing to provide proper antecedent basis for the claimed subject matter, namely for failing to provide proper antecedent basis for the features “an evaporation mechanism, located outside said container,” and “directing means.”

As discussed above, however, at least paragraphs 0023 and 0024 of the application as filed disclose that the film-forming material supply means may be located outside the container. In this case, the evaporation mechanism, which is part of the film-forming material supply means, must necessarily be outside the container.

Further, as discussed above, in paragraphs 0075 and 0089 of the application as originally filed in conjunction with FIG. 26, disclose gas ejection portions 37, which when the valve 19 is opened, eject an inert gas toward the substrate 32 through the gas ejection plate 34. Thus, the specification in conjunction with FIG. 26 provide antecedent basis for a directing means using a transport gas (the inert gas) to direct evaporated film-forming material or the evaporated film-forming material precursor towards the substrate.

Applicants believe that the present application is now in condition for allowance. Favorable reconsideration of the application as amended is respectfully requested. The Examiner is invited to contact the undersigned by telephone if it is felt that a telephone interview would advance the prosecution of the present application.

The Commissioner is hereby authorized to charge any additional fees which may be required regarding this application under 37 C.F.R. §§ 1.16-1.17, or credit any overpayment, to Deposit Account No. 19-0741. Should no proper payment be enclosed herewith, as by the credit card payment instructions in EFS-Web being incorrect or absent, resulting in a rejected or incorrect credit card transaction, the Commissioner is authorized to charge the unpaid amount to Deposit Account No. 19-0741. If any extensions of time are needed for timely acceptance of papers submitted herewith, Applicants hereby petition for such extension under 37 C.F.R. §1.136 and authorizes payment of any such extensions fees to Deposit Account No. 19-0741.

Respectfully submitted,

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